## B. Claims

The following is a complete listing of the claims, and replaces all earlier versions and listings.

(Currently Amended) A thermoelectric conversion material having a
multi-column structure comprising a porous body having columnar pores and a
semiconductor material that can perform thermoelectric conversion introduced into the
pores of the porous body, eharacterized in that

wherein the porous body is formed by removing a column-forming material containing a first component from a structure in which a plurality of columns of the column-forming material are distributed in a matrix containing a second component that is eutectic with the first component, and

wherein the porous body is composed mainly of silicon or germanium.

- (Cancelled)
- (Original) The thermoelectric conversion material according to claim 1, wherein the porous body is in a thin film.
- (Original) The thermoelectric conversion material according to claim 1, wherein the multi-column structure is obtained by further chemically treating the porous body and then introducing the semiconductor material into the pores.

- (Original) The thermoelectric conversion material according to claim 4, wherein the chemical treatment is an oxidation treatment.
- 6. (Original) The thermoelectric conversion material according to claim 1, wherein the first component is aluminum; the second component is silicon; and the structure contains silicon at 20 atomic% or more and 70 atomic% or less
- (Original) The thermoelectric conversion material according to claim 1, wherein the first component is aluminum; the second component is germanium; and the structure contains germanium at 20 atomic% or more and 70 atomic% or less.

## 8-9. (Cancelled)

- (Original) The thermoelectric conversion material according to claim 1, wherein the average diameter of columns in the structure is 0.5 nm or more and 15 nm or less.
- (Currently Amended) The thermoelectric conversion material according to claim 1, wherein the an average spacing of columns in the structure is 5 nm or more and 20 nm or less.

- 12. (Original) The thermoelectric conversion material according to claim 1, wherein part of the column-forming material is a crystalline material, and the matrix is an amorphous material.
- (Currently Amended) A thermoelectric conversion device using comprising a thermoelectric conversion material according to claim 1.
- (Currently Amended) A manufacturing method of a thermoelectric conversion material comprising the steps of:

providing a structure in which a plurality of columns of a column-forming material containing a first component aluminum are distributed in a matrix containing a second component silicon, germanium, or silicon germanium that is cutectic with aluminum the first component;

removing the column-forming material to form a porous body; and introducing a semiconductor material into pores of the porous body.

- (Original) The manufacturing method according to claim 14, comprising a step of chemically treating the porous body after the removal step.
  - 16. (Currently Amended) The manufacturing method according to claim

1415, wherein the chemical treatment is an oxidation treatment.

- 17. (Original) The manufacturing method of thermoelectric conversion material according to any one of claim 14 to 16, wherein the introduction step of the semiconductor is electrodeposition.
- 18. (Withdrawn) A structure comprising a plurality of columns of a column-forming material and a matrix surrounding the columns, wherein the columns have a Seebeck coefficient at a room temperature larger than that of the material in bulk solid.
- 19. (Withdrawn) The structure according to claim 18 wherein the columns are placed on a substrate, and substantially perpendicular to a surface of the substrate.
- 20. (Withdrawn) A thermoelectricity conversion device comprising on a substrate, a structure which comprises columns of a column-forming material and a matrix surrounding the columns, wherein the columns have a Seebeck coefficient larger than that of the material in a bulk solid at room temperature, and the columns are electrically connected to electrodes; and the device generates current flow in response to thermal change of outside.